

In the Claims:

Please cancel claim 20, amend claims 10 and 15 and add new claims 21-23, as set forth in the complete listing of the claims and their status that follows:

1. (Cancelled)
2. (Cancelled)
3. (Cancelled)
4. (Cancelled)
5. (Cancelled)
6. (Cancelled)
7. (Cancelled)
8. (Previously presented) The apparatus of claim 15, wherein said means for preventing retrograde movement includes at least one resilient prong arranged within said track assembly channel to prevent movement of a wafer in said second direction and to deflect as a wafer passes said prong in said first direction.
9. (Previously presented) The apparatus of claim 15, wherein said means for preventing retrograde movement includes a plurality of resilient prongs spaced along the length of said track assembly channel from said introduction end to said discharge end.

10. (Currently amended) The apparatus of claim 9-15, wherein said plurality of resilient prongs are provided in opposing pairs of prongs disposed on opposite sides of said track assembly channel.

11. (Previously presented) The apparatus of claim 15, further comprising an advancement gun supporting said track assembly and having a manually operable trigger operably coupled to said advancement mechanism so that depressing said trigger slides said advancement mechanism in said first direction within said pusher channel.

12. (Previously presented) The apparatus of claim 11, wherein:
said advancement gun includes a housing; and
said trigger is pivotably mounted within said housing.

13. (Previously presented) The apparatus of claim 12, wherein said advancement gun includes a linkage coupled between said trigger and said advancement mechanism, said linkage configured to translate pivoting of said trigger into linear movement of said mechanism within said pusher channel.

14. (Original) The apparatus of claim 12, wherein:
said advancement mechanism includes a rack gear; and
said trigger includes a clock gear arranged to mesh with said rack gear as said trigger is pivoted.

15. (Currently amended) An apparatus for sequentially inserting wafers into a body space of a patient, the apparatus comprising:

a track assembly defining a channel from an introduction end configured to receive wafers, to a an opposite discharge end adapted to be positioned within the body space, said channel configured to sequentially receive the plurality of wafers therein and including;

a first track defining a wafer channel having an opening at said introduction end adapted sized and configured to receive wafers therethrough; and

a second track coupled to said first track and defining a pusher channel;

a cartridge carrying a plurality of wafers, said cartridge coupled to said track assembly at said wafer channel opening so that a wafer from said plurality of wafers enters said introduction end of said track assembly through said wafer channel opening;

an advancement mechanism slidably disposed within said pusher channel of said track assembly and operable on a wafer within said wafer channel to advance the wafer in a first direction along said wafer channel toward said discharge end; and

means for preventing retrograde movement of a wafer within said wafer channel in a second direction opposite said first direction.

16. (Original) The apparatus of claim 15, wherein said advancement mechanism includes a portion slidably disposed within said pusher channel and at least one finger projecting from said portion into said wafer channel to push a wafer disposed within said wafer channel.

17. (Original) The apparatus of claim 15, wherein:
said pusher channel defines discharge opening at said discharge end for discharge of a wafer into the body space;

said wafer channel communicates with said pusher channel adjacent said discharge end; and

said track assembly includes means for diverting a wafer from said wafer channel into said pusher channel as the wafer is conveyed along said wafer channel.

18. (Original) The apparatus of claim 17, wherein said means for diverting includes a spring arm mounted within said wafer channel and arranged to guide a wafer from said wafer channel to said pusher channel.

19. (Original) The apparatus of claim 17, wherein said advancement mechanism includes:

a portion slidably disposed within said pusher channel and arranged to push a wafer within said pusher channel to said discharge opening; and

at least one finger projecting from said portion into said wafer channel to push a wafer disposed within said wafer channel.

20. (Cancelled)

21. (New) The apparatus of claim 11, further comprising means for removably mounting said track assembly, with said cartridge coupled thereto, to said advancement gun.

22. (New) The apparatus of claim 21, wherein said means for removably mounting includes a pair of locking cams disposed on said cartridge and a pair of latches pivotably mounted to said advancement gun and pivotable to engage said pair of locking cams.

23. (New) The apparatus of claim 21, wherein said advancement gun includes a linkage coupled to said trigger and configured to engage said advancement mechanism when said track assembly is mounted to said gun, said linkage configured to translate pivoting of said trigger into linear movement of said mechanism within said pusher channel.